

STRUCTURAL CHARACTERIZATION BY XRD OF $Zn_xCd_{1-x}S$ FILMS GROWTH BY CHEMICAL BATH DEPOSITION (CBD)

J. Martínez^a, O. Portillo-Moreno^b, R. Lozada-Morales^c, G. Juárez^d, R. Palomino^c, R. Galeazzi^a, H.Lima-Lima^b, F. Flores^a.

^a CIDS-ICUAP, Benemérita Universidad Autónoma de Puebla, Puebla, México.

^b Fac. Ciencias químicas, Benemérita Universidad Autónoma de Puebla, Puebla, México

^c Fac. Físico-Matemáticas, Benemérita Universidad Autónoma de Puebla, Puebla, México.

^d Ingeniería Eléctrica, SEES-CINVESTAV, Unidad D. F. México.

Abstract

A Structural analysis by XRD of $Zn_xCd_{1-x}S$ films was made, the films was deposited on glass substrates by Chemical Bath Deposition technique (CBD) at temperatures of: $T = 85 \pm 2^\circ\text{C}$, varying the volume of the solution (x) that contains the Zn^{2+} to obtain: $x = 5, 10, \dots, 40$. The film thicknesses are in the 2000-2400 nm interval measured using a profile meter. The percentage of Zn atoms varies respect to x in the range of 3,8-48,34% quantified by means of Scanning Electron Microscopy (SEM). By means of x-ray Diffraction was found the phase and preferential direction in which deposit the films, from diffractograms was determined the grain size (GS), using the Scherrer equation, varies 30-7,5 nm and the interplanar distance d) is modified between 3.338-3.330 Å.